

PATENT
0965-0413P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: YANAGIDA, Hisashi Conf.:
Appl. No.: NEW Group:
Filed: August 29, 2003 Examiner:
For: ELECTROSTATIC CHUCK SUPPORT MECHANISM,
SUPPORT STAND DEVICE AND PLASMA
PROCESSING EQUIPMENT

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 29, 2003

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

This reply includes:

Amendments to the Claims

Remarks